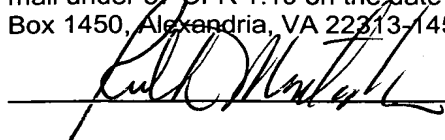


EXPRESS MAIL No.: **EV 304 055 847 US**

Deposited: **February 23, 2004**

I hereby certify that this correspondence is being deposited with the United States Postal Service Express mail under 37 CFR 1.10 on the date indicated above and is addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450



/ **Ruth Montalvo** Date: **02/23/04**

Customer No. 026418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket No. GK-OEH-178 / 500814.20080

Applicant(s): Duc Chinc TRAN and Juergen KLEINSCHMIDT

Application No.:

Filed: Concurrently herewith

For: **ARRANGEMENT FOR DEBRIS REDUCTION IN A RADIATION
SOURCE BASED ON A PLASMA**

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

S I R:

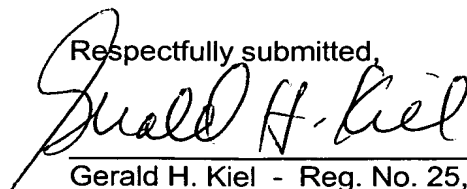
Applicant herewith submits together with the simultaneously patent application this Information Disclosure Statement in accordance with the provisions of 37 C.F.R. §§ 1.97 and 1.98, and hereby make of record the following references:

	Document Number	Date	Name and/or Country	English Translation
AA	6,359,969	03/19/2002	Shmaenok	
AB	6,377,651	04/23/2002	Richardson, et al.	
AL	102 15 469	11/06/2003	Germany	US equivalent 2003 / 0190012
AV	Proceedings of SPIE, Vol. 4146 (2000) pgs. 128-131, Yamamoto et al.			
	"Compact Debris Shutter Design of a laser-Produced Plasma Source for High NA Application"			

Accompanying this Information Disclosure Statement and form PTO-1449 are copies of the documents. All document are mentioned on page 2 of the specification.

This submission is not an admission that the information disclosed in the documents is material to the patentability of the invention disclosed and/or claimed in the above-identified application.

Respectfully submitted,



Gerald H. Kiel - Reg. No. 25,116
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599 Lexington Avenue
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02/23/04
GHK:ram

Tel. (212) 521-5400

Enclosures:
PTO-1449,
3 documents & US Equivalent

LIST OF PRIOR ART CITED BY APPLICANT
(Filed on February 23, 2004)

Docket No. GK-OEH-178 / 500814.20080

Applicant(s): Duc Chinc TRAN and Juergen KLEINSCHMIDT

Application No.

Group:

Filed: concurrently herewith -February 23, 2004

Examiner:

U.S. PATENT DOCUMENTS

Exam. Init		Document Number	Date	Name	Class	Sub-Class	Filing Date Appropriate
	AA	6,359,969	03/19/2002	Shmaenok			
	AB	6,377,651	04/23/2002	Richardson, et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	CLASS	Sub-Class	Translation YES NO
	AL	102 15 469	11/06/2003	Germany			US 2003/0190012
	AM						
	AN						
	AO						
	AP						
	AQ						
	AR						
	AS						

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	AV	Proceedings of SPIE, Vol. 4146 (2000) pgs. 128-131, Yamamoto et al. "Compact Debris Shutter Design of a laser-Produced Plasma Source for High NA Application"
	AW	
	AX	
	AY	
	AZ	

Examiner:

Date:

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.